



J. Ruggles

110735

Group Art Unit: 1756

Examiner:

Docket No.:

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Akifumi KAMIJIMA et al.

Application No.: 09/966,080

Filed: October 1, 2001

A METHOD FOR FABRICATING A RESIST PATTERN, A METHOD FOR

PATTERNING A THIN FILM AND A METHOD FOR MANUFACTURING A

MICRO DEVICE

AMENDMENT UNDER 37 C.F.R. §1.111

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

For:

In reply to the March 26, 2003 Office Action, please consider the following:

Amendments to the Claims are reflected in the listing of claims;

Amendments to the Drawings include attached replacement sheets; and

Remarks.